EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L5	4538	switch$3 with gas with liquid	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/17 12:03
L11	57250	retaining adj ring	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/17 12:10
L12	2	l11 and l5 and (wafer semiconductor substrate)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/17 12:10
L13	669	l11 and (moist$4 with (air gas))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/17 12:10
L15	144	l13 and (wafer substrate semiconductor)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/17 12:13
L16	18	l13 and (cmp (chemical adj mechanical adj polish$4))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/17 12:15
L17	215	(moist$4 adj (gas air)) and (cmp (chemical adj mechanical adj polish$4))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/17 12:15

3/17/07 12:35:21 PM

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C:\Documents and Settings\mrachuba\My Documents\EAST\Workspaces\10539245 retaining ring with openings for temp controlled gas 2.

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S22	9951	(slot opening hole) with (retaining adj ring)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 13:56
S23	623	S22 and (wafer substrate semiconductor)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 13:56
S24	376	S23 and (fluid gas)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 13:56
S25	89	S24 and cleaning	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 13:57
S26	3484673	wafer substrate semiconductor	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/16 11:28
S27	2499720	holder carrier	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/16 11:28